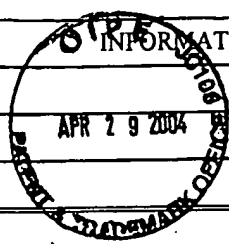


U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
					2003-0125-01		10/803,526	
<div style="text-align: center;">  <p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p> <p>(Use several sheets if necessary)</p> </div>					Applicant(s)			
					Robert P. Akins, et al.			
					Filing Date		Group	
					March 17, 2004		Unassigned 2881	
U.S. Patent Documents								
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len	A	2,759,106	8/14/56	Hans Wolter	250	53		
	B	3,150,483	5/10/62	Mayfield, et al.	60	35.5		
	C	3,232,046	2/1/66	Rudolf Meyer	50	35.5		
	D	3,279,176	10/18/66	Robert H. Boden	60	202		
	E	3,746,870	7/17/73	Donald M. Demarest	250	227		
	F	3,960,473	6/1/76	Thomas Harris	425	467		
	G	3,961,197	6/1/76	John M. Dawson	250	493		
	H	3,969,628	7/13/76	Roberts, et al.	250	402		
	I	4,042,848	8/16/77	Ja Hyun Lee	313	231.6		
	J	4,088,966	5/9/78	Michael A. Samis	313	231.5		
	K	4,143,275	3/6/79	Mallozzi, et al.	250	503		
	L	4,162,160	7/24/79	Gerald J. Witter	75	246		
	M	4,203,393	5/20/80	Dante S. Giardini	123	30		
	N	4,504,964	3/12/85	Cartz, et al.	378	119		
	O	4,536,884	8/20/85	Weiss, et al.	378	119		
	P	4,538,291	8/27/85	Seiichi Iwamatsu	378	119		
	Q	4,596,030	6/17/86	Herziger, et al.	378	119		
	R	4,618,971	10/21/86	Weiss, et al.	378	34		
	S	4,626,193	12/2/86	Ronald A. Gann	431	71		
	T	4,633,492	12/30/86	Weiss, et al.	378	119		
len	U	4,635,282	1/6/87	Okada, et al.	378	34		
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							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
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en	V	4,751,723	6/14/88	Gupta, et al.	378	119	
	W	4,752,946	6/21/88	Gupta, et al.	378	119	
	X	4,837,794	6/6/89	Riordan, et al.	378	119	
	Y	5,023,897	6/11/91	Neff, et al.	378	122	
	Z	5,027,076	6/25/91	Horsley, et al.	324	674	
	AA	5,102,776	4/7/92	Hammer et al.	430	311	
	BB	5,126,638	6/30/92	Rolf Dethlefsen	315	326	
	CC	5,142,166	8/25/92	Daniel L. Birx	307	419	
	CC	5,313,481	5/17/94	Cook et al.	372	37	
	DD	5,411,224	5/2/95	Dearman, et al.	244	53	
	EE	5,448,580	9/5/95	Birx et al.	372	38	
	FF	5,504,795	4/2/96	Malcolm McGeoch	378	119	
	GG	5,729,562	3/17/98	Birx et al.	372	38	
	HH	5,763,930	6/9/98	William N. Partlo	250	504	
	II	5,866,871	2/2/99	Daniel L. Birx	219	121	
	JJ	5,936,988	8/10/99	Partlo et al.	372	38	
	KK	5,963,616	10/5/99	Silfvast, et al.	378	122	
	LL	6,031,241	2/29/00	Silfvast, et al.	250	504	
	MM	6,039,850	3/21/00	Stephen C. Schulz	204	192.15	
en	NN	6,172,324	1/9/01	Daniel L. Birx	219	121.57	

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Examiner <i>en</i>	Date Considered <i>01-10-06</i>
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len	OO	6,051,841	4/18/00	William N. Partlo	250	504		
	PP	6,064,072	5/16/00	Partlo, et al.	250	504		
	QQ	6,195,272	2/27/01	Joseph E. Pascente	363	21		
	RR	6,452,199	9/7/02	Partlo, et al.	250	504		
	SS	6,566,667	5/20/03	Partlo, et al.	250	504		
	TT	6,566,668	5/20/03	Rauch, et al.	250	504		
	UU	6,576,912	6/10/03	Visser, et al.	250	492.2		
	VV	6,586,757	7/1/03	Melnychuk, et al.	250	504		
	WW	2001/0055364	12/27/01	Kandaka, et al.	378	119		
	XX	2002/0100882	8/1/02	Partlo, et al.	250	504		
	AA	2002/0163313	1/9/03	Ness, et al.	315	111.01		
	AB	2002/0168049	11/14/02	Schriever, et al.	378	119		
	AC	2003/0006383	1/9/03	Melnychuk, et al.	250	504		
	AD	2003/0068012	4/10/03	Ahmad, et al.	378	119		
len	AE	2003/0219056	11/27/03	Yager, et al.	372	57		
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	AG	Apruzese, J.P., "X-Ray Laser Research Using Z Pinches," <u>Am. Inst. of Phys.</u> 399-403, (1994).						
	AH	Bollanti, et al., "Compact Three Electrodes Excimer Laser IANUS for a POPA Optical System," <u>SPIE Proc.</u> (2206)144-153, (1994).						
	AI	Bollanti, et al., "Ianus, the three-electrode excimer laser," <u>App. Phys. B (Lasers &amp; Optics)</u> 66(4):401-406, (1998).						
	AJ	Choi, et al., "A 10 <sup>13</sup> A/s High Energy Density Micro Discharge Radiation Source," <u>B. Radiation Characteristics</u> , p. 287-290.						
	AK	Choi, et al., "Fast pulsed hollow cathode capillary discharge device," <u>Rev. of Sci. Instrum.</u> 69(9):3118-3122 (1998).						
	AL	Fomenkov, et al., "Characterization of a 13.5nm Source for EUV Lithography based on a Dense Plasma Focus and Lithium Emission." <u>Sematech Intl. Workshop on EUV Lithographv</u> (Oct. 1999).						
	AM	Hansson, et al., "Xenon liquid jet laser-plasma source for EUV lithography," <u>Emerging Lithographic Technologies IV, Proc. Of SPIE</u> , Vol. 3997:729-732 (2000).						
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	AP	Lebert, et al., "Soft x-ray emission of laser-produced plasmas using a low-debris cryogenic nitrogen target," <u>J. App. Phys.</u> , 84(6):3419-3421 (1998).						
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	AR	Lebert, et al., "Investigation of pinch plasmas with plasma parameters promising ASE," <u>Inst. Phys. Conf. Ser No. 125: Section 9</u> , pp. 411-415 (1992) Schiersee, Germany.						
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	AX	Mayo, et al., "A magnetized coaxial source facility for the generation of energetic plasma flows," <u>Sci. Technol.</u> Vol. 4:pp.47-55 (1994).						
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	BA	Orme, et al., "Electrostatic charging and deflection of nonconventional droplet streams formed from capillary stream breakup," <u>Physics of Fluids</u> , 12(9):2224-2235, (September 2000).						
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	BC	Pant, et al., "Behavior of expanding laser produced plasma in a magnetic field," <u>Physica Scripta</u> , T75:104-111, (1998).						
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	BI	Schriever, et al., "Laser-produced lithium plasma as a narrow-band extended ultraviolet radiation source for photoelectron spectroscopy," <u>App. Optics</u> , 37(7):1243-1248. (Mar. 1998).						
	BJ	Schriever, et al., "Narrowband laser produced extreme ultraviolet sources adapted to silicon/molybdenum multilayer optics," <u>J. of App. Phys.</u> 83(9):4566-4571 (May 1998).						
	BK	Silfvast, et al., "High-power plasma discharge source at 13.5 nm and 11.4 nm for EUV lithography," <u>SPIE</u> , Vol. 3676:272-275. (Mar. 1999).						
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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)									
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	BN	Wilhein, et al., "A slit grating spectrograph for quantitative soft x-ray spectroscopy," Am. Inst. Of Phys. Rev. of Sci. Instrum., 70(3):1694-1699, (Mar. 1999).							
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<i>len</i>	BP	Zombeck, M.V., "Astrophysical Observations with High Resolution X-ray Telescope," Am. Inst. Of Phys., pp. 200-209, (1981).							
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